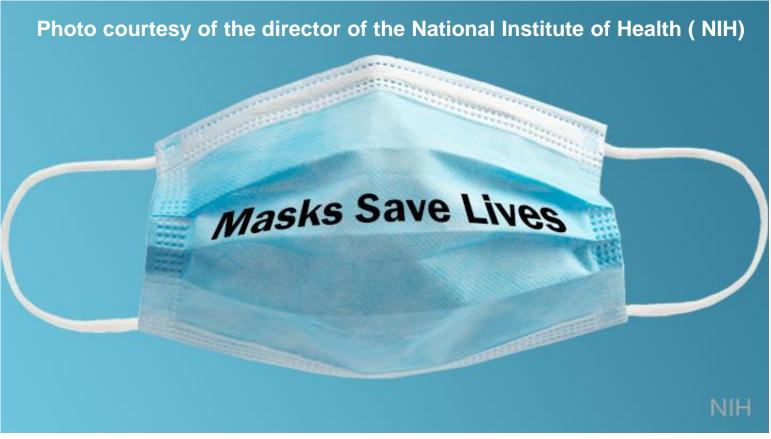
EE 330 Lecture 19

Bipolar Device Operation and Modeling

Exam Schedule

Exam 1 Exam 2 Exam 3 Final Friday Sept 24 Friday Oct 22 Friday Nov 19 Tues Dec 14 12:00 p.m.

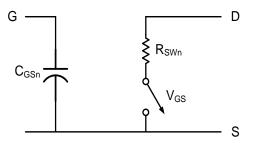


As a courtesy to fellow classmates, TAs, and the instructor

Wearing of masks during lectures and in the laboratories for this course would be appreciated irrespective of vaccination status

Review from last lecture

Model Relationships



Determine R_{SW} and C_{GS} for an n-channel MOSFET from square-law model in the 0.5u ON CMOS process if L=1u, W=1u (Assume $\mu_n C_{OX}$ =100 μ AV⁻², C_{OX} =2.5fFu⁻², V_{T0} =1V, V_{DD} =3.5V, V_{SS} =0)

When on operating in deep triode

$$I_{D} = \mu C_{OX} \frac{W}{L} \left(V_{GS} - V_{T} - \frac{V_{DS}}{2} \right) V_{DS} \cong \mu C_{OX} \frac{W}{L} \left(V_{GS} - V_{T} \right) V_{DS}$$

$$R_{SQ} = \frac{V_{DS}}{I_{D}} \bigg|_{V_{GS} = V_{DD}} = \frac{1}{\mu C_{OX} \frac{W}{L} \left(V_{GS} - V_{T} \right)} \bigg|_{V_{GS} = 3.5V} = \frac{1}{(10^{-4}) \left(\frac{1}{1} \right) (3.5 - 1)} = 4K\Omega$$

 $C_{GS} = C_{OX}WL = (2.5fF\mu^{-2})(1\mu^2) = 2.5fF$

Review from last lecture Model Relationships $G_{GSP} \rightarrow V_{GS}$

Determine R_{SW} and C_{GS} for an p-channel MOSFET from square-law model in the 0.5u ON CMOS process if L=1u, W=1u

 $(\mu_p C_{OX} = \frac{1}{3} \mu_n C_{OX}, \ \mu_n C_{OX} = 100 \mu AV^{-2}, \ C_{OX} = 2.5 \text{fFu}^{-2}, V_{T0} = 1V, \ V_{DD} = 3.5V, \ V_{SS} = 0)$

$$-I_{D} = \mu_{p}C_{OX} \frac{W}{L} \left(V_{GS} - V_{T} - \frac{V_{DS}}{2} \right) V_{DS} \cong \mu_{p}C_{OX} \frac{W}{L} \left(V_{GS} - V_{T} \right) V_{DS}$$
$$R_{SQ} = \frac{-V_{DS}}{-I_{D}} \bigg|_{V_{GS} = V_{DD}} = \frac{1}{\mu_{p}C_{OX} \frac{W}{L} \left(V_{GS} - V_{T} \right)} \bigg|_{V_{GS} = 3.5V} = \frac{1}{\left(\left(\frac{1}{3} \right) 10^{-4} \right) \left(\frac{1}{1} \right) |3.5 - 1|} = 12K\Omega$$

 $C_{GS} = C_{OX}WL = (2.5fF\mu^{-2})(1\mu^2) = 2.5fF$

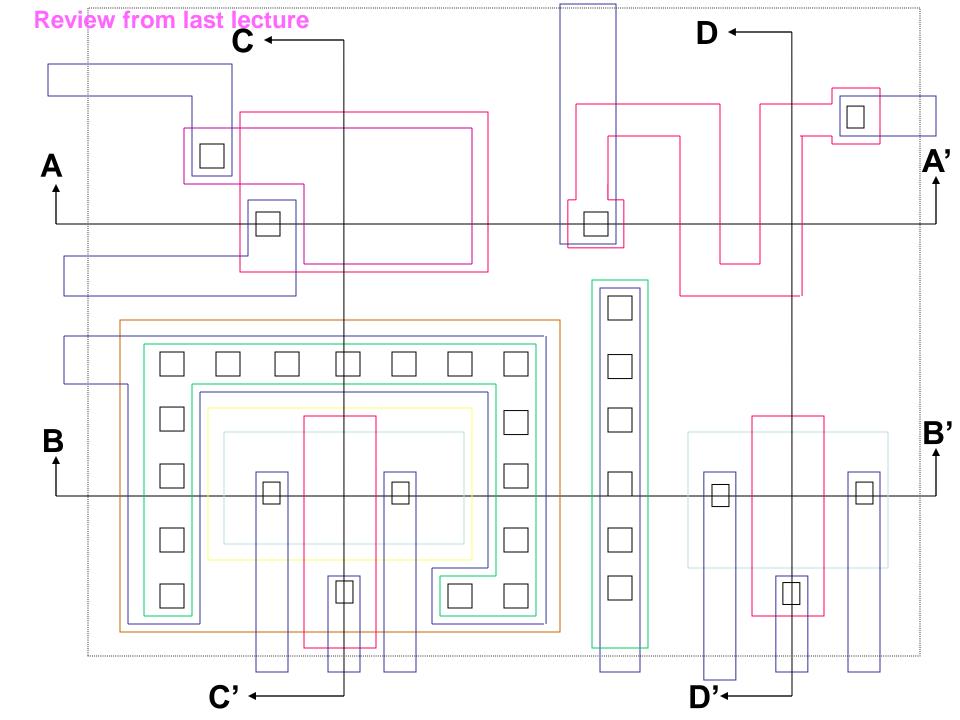
Observe the resistance of the p-channel device is approximately 3 times larger than that of the n-channel device for same bias and dimensions !

This is due to the difference in mobility between n-type and p-type materials

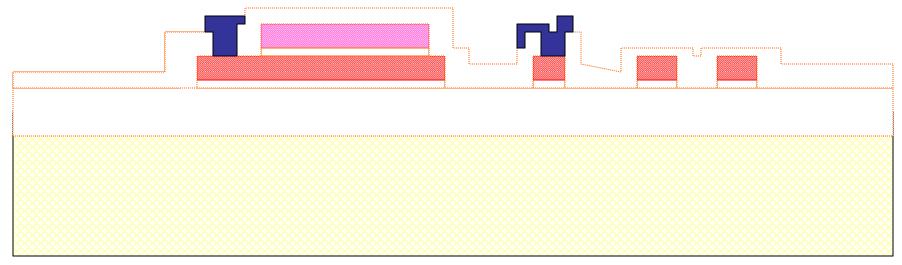
Review from last lecture

TABLE 2B.1 Process scenario of major process steps in typical n-well CMOS process^a

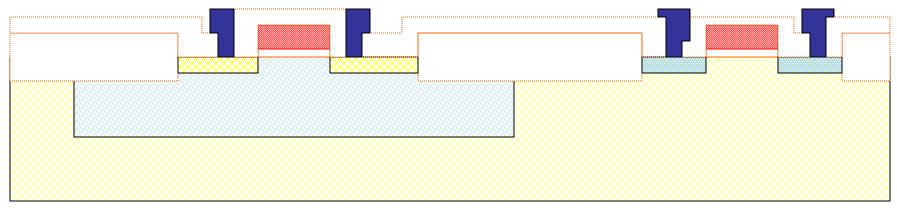
1.	Clean wafer	
2.	GROW THIN OXIDE	
3.	Apply photoresist	
4.	PATTERN n-well	(MASK #1)
5.	Develop photoresist	
6.	Deposit and diffus n-type impurities	
7.	Strip photoresist	
8.	Strip thin oxide	
9.	Grow thin oxide	
10.	Apply layer of Si ₃ N ₄	
11.	Apply photoresist	
12.	PATTERN Si ₃ N ₄ (active area definition)	(MASK #2)
13.	Develop photoresist	
14.	Etch Si ₃ N ₄	
15.	Strip photoresist	
	Optional field threshold voltage adjust	
	A.1 Apply photoresist	
	A.2 PATTERN ANTIMOAT IN SUBSTRATE	(MASK #A1)
	A.3 Develop photoresist	
	A.4 FIELD IMPLANT p-type)	
	A.5 Strip photoresist	
16.	GROW FIELD OXIDE	
17.	Strip Si ₃ N ₄	
18.	Strip thin oxide	
19.	GROW GATE OXIDE	
20.	POLYSILICON DEPOSITION (POLY I)	
21.	Apply photoresist	
22.	PATTERN POLYSILICON	(MASK #3)
23.	Develop photoresist	
24.	ETCH POLYSILICON	



Review from last lecture Metal Mask



A-A' Section



B-B' Section

Review from last lecture

Should now know what you can do in this process !!

Can metal connect to active?

Can metal connect to substrate when on top of field oxide?

How can metal be connected to substrate?

Can poly be connected to active under gate?

Can poly be connected to active any place?

Can metal be placed under poly to isolate it from bulk?

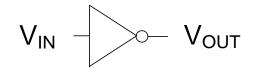
Can metal 2 be connected directly to active?

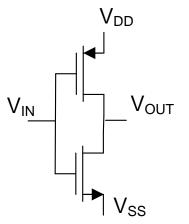
Can metal 2 be connected to metal 1?

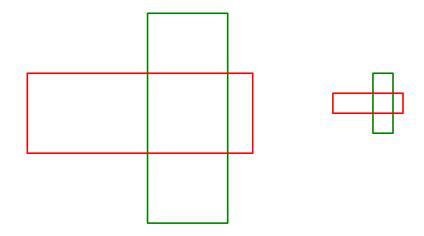
Can metal 2 pass under metal 1?

Could a process be created that will result in an answer of YES to most of above?

How does the inverter delay compare between a 0.5u process and a 0.18u process?







RUN: T91T TECHNOLOGY: SCN05

Run type: SKD

VENDOR: AMIS EATURE SIZE: 0.5 microns

INTRODUCTION: This report contains the lot average results obtained by MOSIS from measurements of MOSIS test structures on each wafer of this fabrication lot. SPICE parameters obtained from similar measurements on a selected wafer are also attached.

COMMENTS: American Microsystems, Inc. C5

TRANSISTOR	PARAMETERS	W/L	N-CHANNEL	P-CHANNEL	UNITS
MINIMUM Vth		3.0/0.6	0.81	-0.92	volts
SHORT		20.0/0.6			
Idss			466	-250	uA/um
Vth			0.69	-0.89	volts
Vpt			12.7	-11.7	volts
WIDE		20.0/0.6			
Ids0			< 2.5	< 2.5	pA/um
LARGE		20.0/20.0			
Vth			0.71	-0.94	volts
Vjbkd			8.8	-11.7	volts
Ijlk			<50.0	<50.0	рА
Gamma			0.44	0.57	v^0.5
K' (Vo*Cox Low-field			54.8 434.84	-19.7 156.32	uA/V^2 cm^2/V*s

PROCESS PARAMETERS Sheet Resistance Contact Resistance Gate Oxide Thickness	N+ 85.3 59.6 137	P+ 111.2 145.4	POLY 22.4 17.9	PLY2_HR 1033	м1 0.09	UNITS ohms/sq ohms angstroms
CAPACITANCE PARAMETERS Area (substrate) Area (N+active) Area (P+active) Area (poly)	N+ 443	р+ 745	POLY 102 2518 2441	POLY2 896	м1 61	UNITS aF/um^2 aF/um^2 aF/um^2 aF/um^2
CIRCUIT PARAMETERS Ring Oscillator Freq. DIV256 (31-stg,5.0V) Ring Oscillator Power DIV256 (31-stg,5.0V)			UNIT .47 MHz .48 uW/M	CS Mz/gate		

MOSIS WAFER ACCEPTANCE TESTS

RUN: T4BK (MM_NON-EPI_THK-MTL) TECHNOLOGY: SCN018 VENDOR: TSMC FEATURE SIZE: 0.18 microns

INTRODUCTION: This report contains the lot average results obtained by MOSIS from measurements of MOSIS test structures on each wafer of this fabrication lot. SPICE parameters obtained from similar measurements on a selected wafer are also attached.

COMMENTS: DSCN6M018_TSMC

TRANSISTOR PARAMETERS	W/L	N-	CHANNEL	P-CHANNEL	UNITS
MINIMUM Vth	0.27/0.18		0.50	-0.53	volts
SHORT	20.0/0.18				
Idss			571	-266	uA/um
Vth			0.51	-0.53	volts
Vpt			4.7	-5.5	volts
WIDE	20.0/0.18				
Ids0			22.0	-5.6	pA/um
LARGE	50/50				
Vth			0.42	-0.41	volts
Vjbkd			3.1	-4.1	volts
Ijlk			<50.0	<50.0	pА
K' (Uo*Cox/2)		Г	171.8	-36.3	uA/V^2
Low-field Mobility			398.02	84.10	cm^2/V*s

CAPACITANCE PARAMETERS Area (substrate) Area (N+active)	N+ 998	P+ 1152	103 8566	39	19	13	M4 9 11	8	M6 3 9	R_W	D_N_W 129	M5P	N_W 127	UNITS aF/um^2 aF/um^2
Area (P+active) Area (poly)			8324	64	18	10	7	6	5					aF/um^2 aF/um^2
Area (metal1)					44	16	10	7	5					aF/um^2
Area (metal2)						38	15	9	7					aF/um^2
Area (metal3)							40	15	9					aF/um^2
Area (metal4)								37	14					aF/um^2
Area (metal5)									36			1003		aF/um^2
Area (r well)	987													aF/um^2
Area (d well)										574				aF/um^2
Area (no well)	139													aF/um^2
Fringe (substrate)	244	201					43							aF/um
Fringe (poly)				69			24							aF/um
Fringe (metal1)					61	35	~ -		21					aF/um
Fringe (metal2)						54	37							aF/um
Fringe (metal3)							56	34						aF/um
Fringe (metal4)								58	40 61					aF/um
Fringe (metal5) Overlap (P+active)			652						91					aF/um aF/um
			052											ar / ulli
CIRCUIT PARAMETERS							UNI.	TS						
Inverters			<											
Vinv			.0	(ð.74	4	vol	ts						
Vinv		1	. 5	(ð.78	8	vol	ts						
Vol (100 uA)		2	.0	(0.08	8	vol	ts						
Voh (100 uA)		2	.0		1.63	3	vol	ts						
Vinv		2	.0	(0.82	2	vol	ts						
Gain		2	.0	-2	3.33	3								
Ring Oscillator Freq.														
D1024_THK (31-s+g_3							MH⁊	•						
DIV1024 (31-stg,1.8V				40	2.84	4	MHz							
Ring Oscillator Power						_			, .					

 D1024_THK (31-stg,3.3V)
 0.07
 uW/MHz/gate

 DIV1024 (31-stg,1.8V)
 0.02
 uW/MHz/gate

How does the inverter delay compare between a 0.5u process and a 0.18u process?

Feature	0.5	0.18	Units
Vtn	0.81	0.5	V
Vtp	-0.92	-0.53	V
uCoxn	109.6	344	uA/V^2
uCoxp	39.4	72.6	uA/V^2
Сох	2.51	8.5	fF/µm^2
Vdd	5	1.8	V
fosc-31	94.5	402.8	MHz

Assume n-channel and p-channel devices with L=Lmin, W=1.5Lmin

0.18

0.83

1491

3941

1.23

3.26

223

0.5

1.88

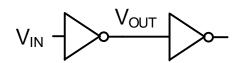
1452

2858

2.73

5.38

123



$t_{HL} = R_{pd}C_L$	
$t_{LH} = R_{pd}C_L$	

Feature

CL

Rpd

Rpu

THL

TLH

f

$$R_{pd} = \frac{L_n}{\mu_n C_{OX} W_n (V_{DD} - V_{TN})}$$

$$R_{pu} = \frac{L_p}{\mu_p C_{OX} W_p (V_{DD} + V_{TP})}$$
0.18 Units

fF

ohms

ohms

psec

psec

GHz

$$\boldsymbol{C}_{L} = \boldsymbol{C}_{OX} \left(\boldsymbol{W}_{n} \boldsymbol{L}_{n} + \boldsymbol{W}_{p} \boldsymbol{L}_{p} \right)$$

Note 0.18u process is much faster than 0.5u process
Some scale even faster

Basic Devices and Device Models

- Resistor
- Diode
- Capacitor
- MOSFET
- BJT

Lets pick up a discussion of Technology Files before moving to BJT **Return to basic devices !**

Basic Devices and Device Models

- Resistor
- Diode
- Capacitor
- MOSFET



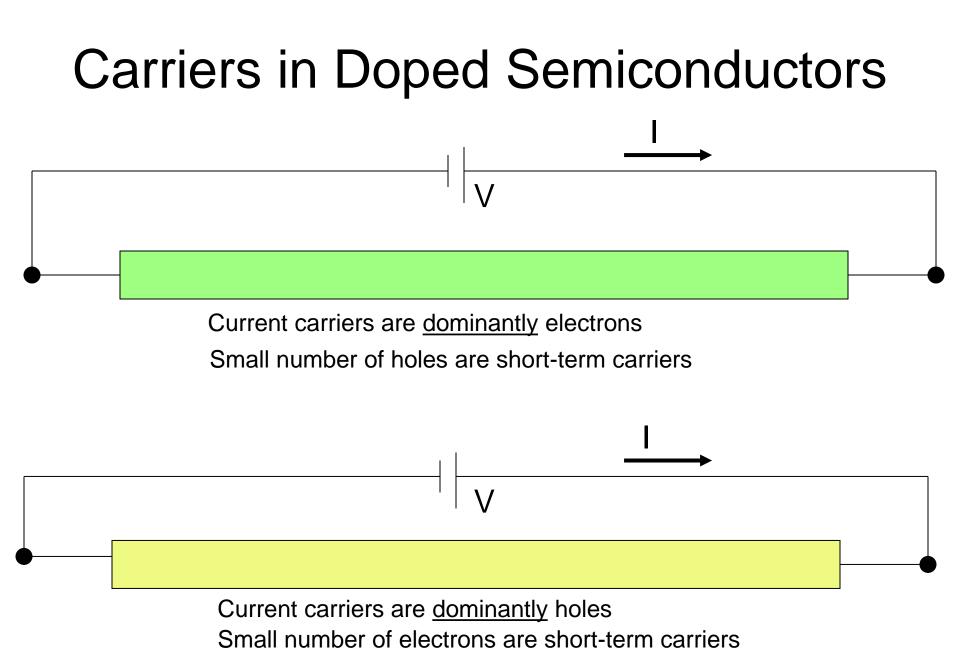
Bipolar Junction Transistors

- Operation
- Modeling

Carriers in Doped Semiconductors

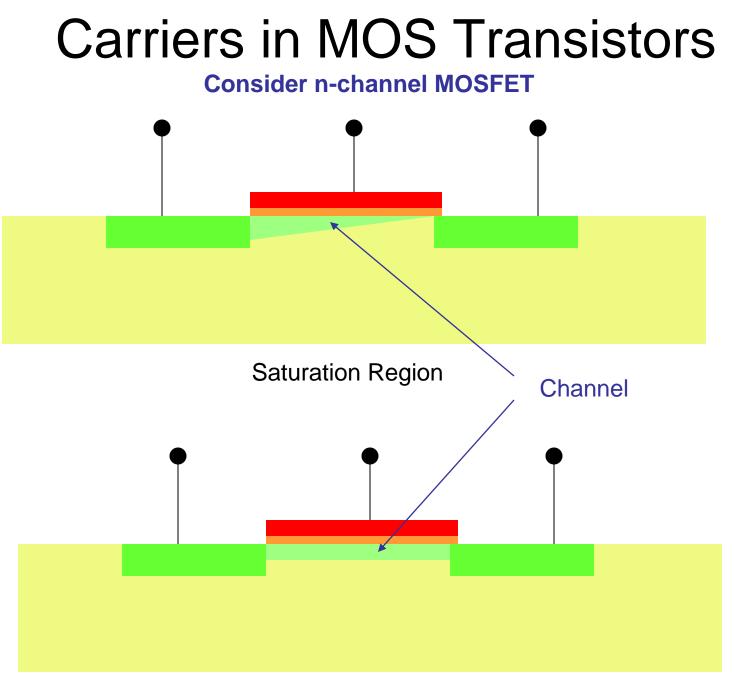
n-type

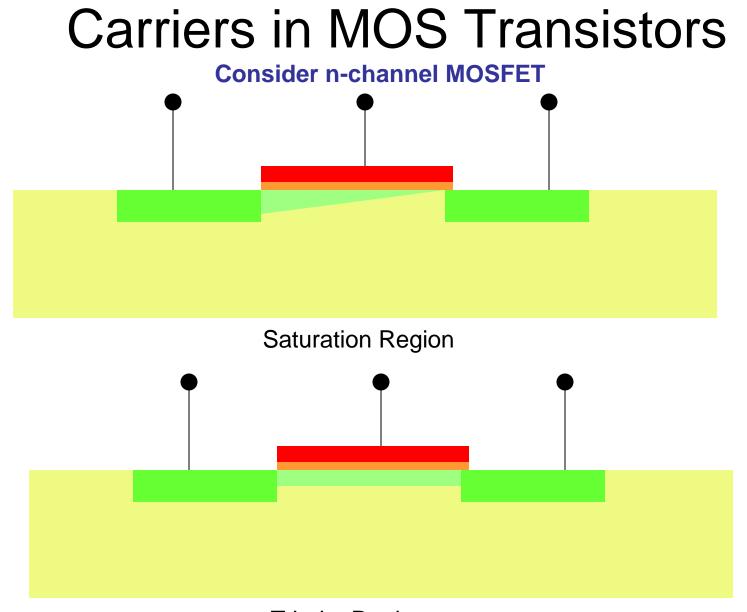
p-type



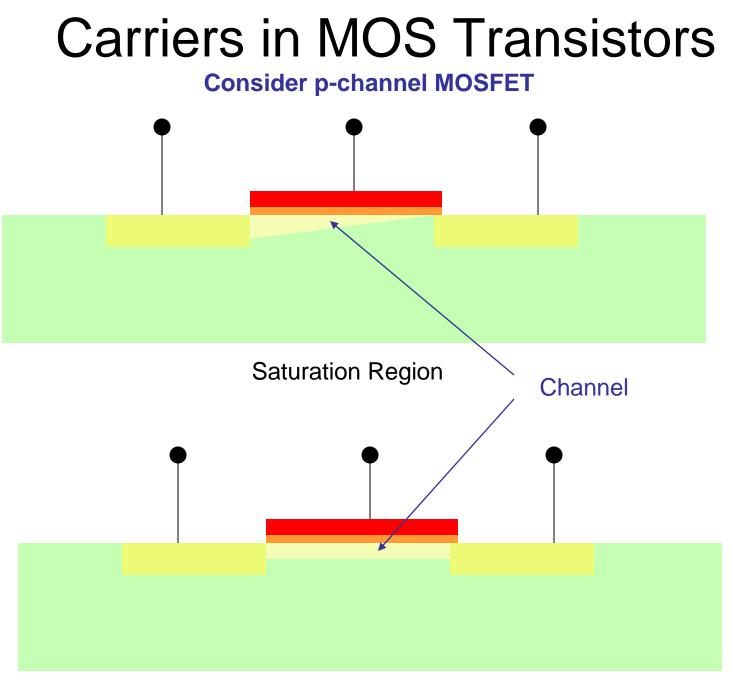
Carriers in Doped Semiconductors

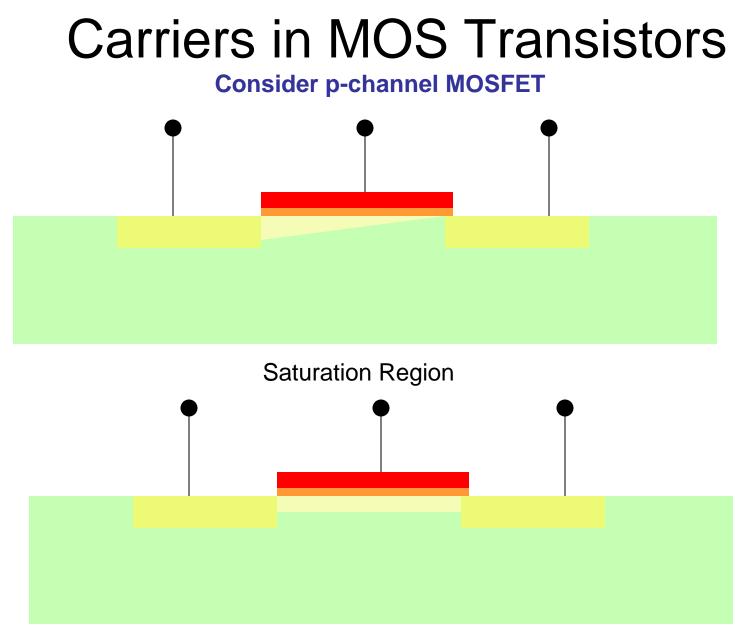
	Majority Carriers	Minority Carriers
n-type	electrons	holes
p-type	holes	electrons





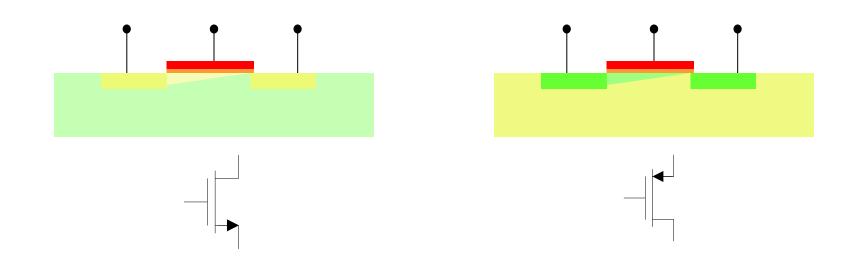
Carriers in electrically induced n-channel are electrons



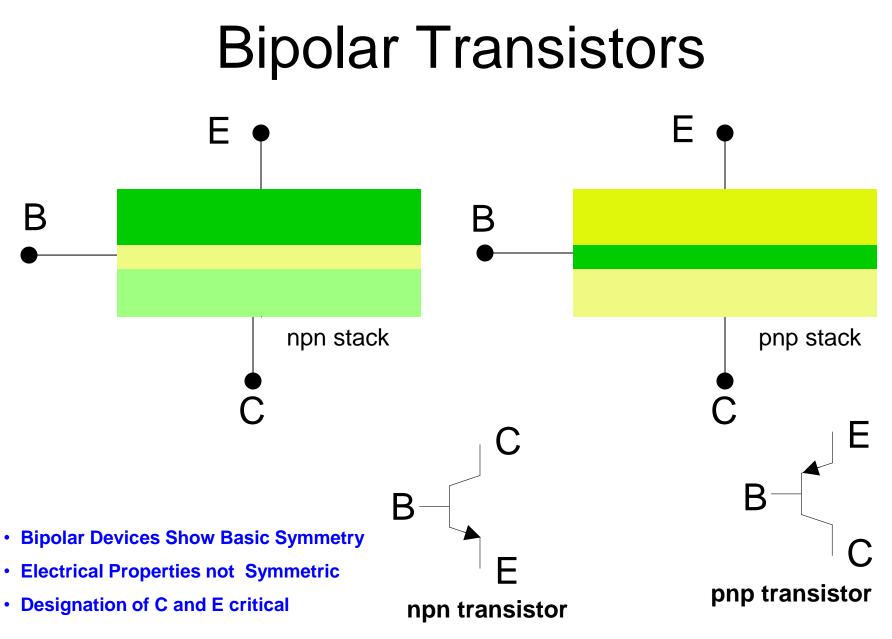


Carriers in electrically induced p-channel are holes

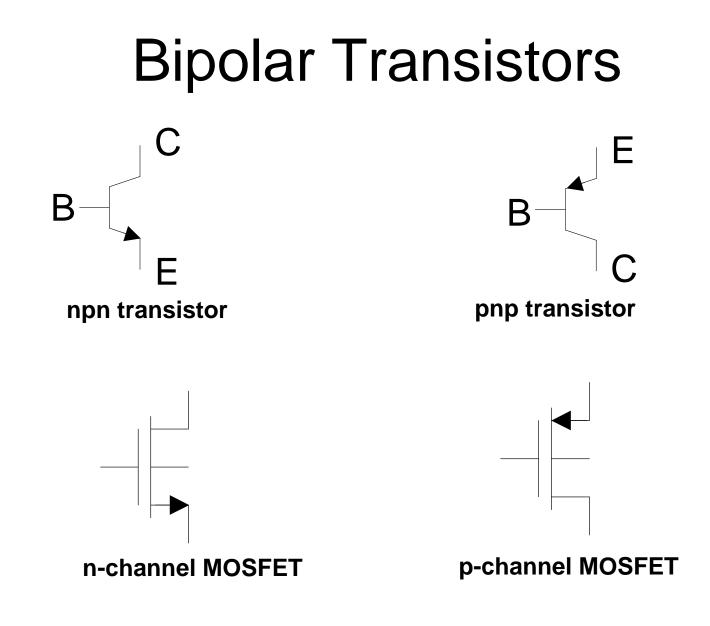
Carriers in MOS Transistors



Carriers in channel of MOS transistors are Majority carriers

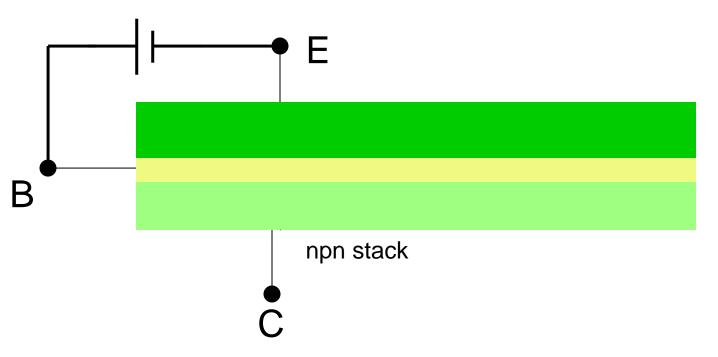


With proper doping and device sizing these form Bipolar Transistors



In contrast to a MOSFET which has 4 terminals, a BJT only has 3 terminals

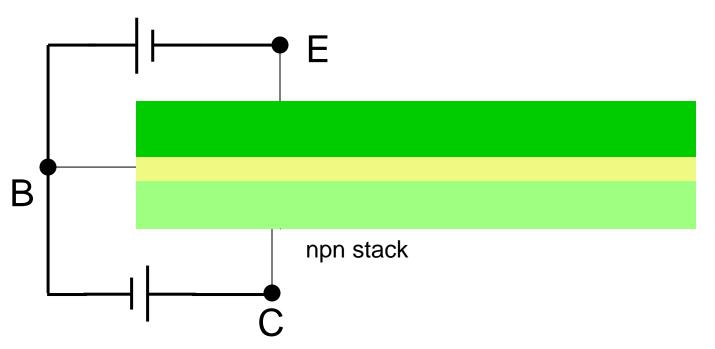
Consider npn transistor – Forward Active Operation



Under forward BE bias current flow into base and out of emitter

- Current flow is governed by the diode equation
- Carriers in emitter are electrons (majority carriers)
- When electrons pass into the base they become minority carriers
- Quickly recombine with holes to create holes base region
- Dominant current flow in base is holes (majority carriers)

Bipolar Operation Consider npn transistor – Forward Active Operation



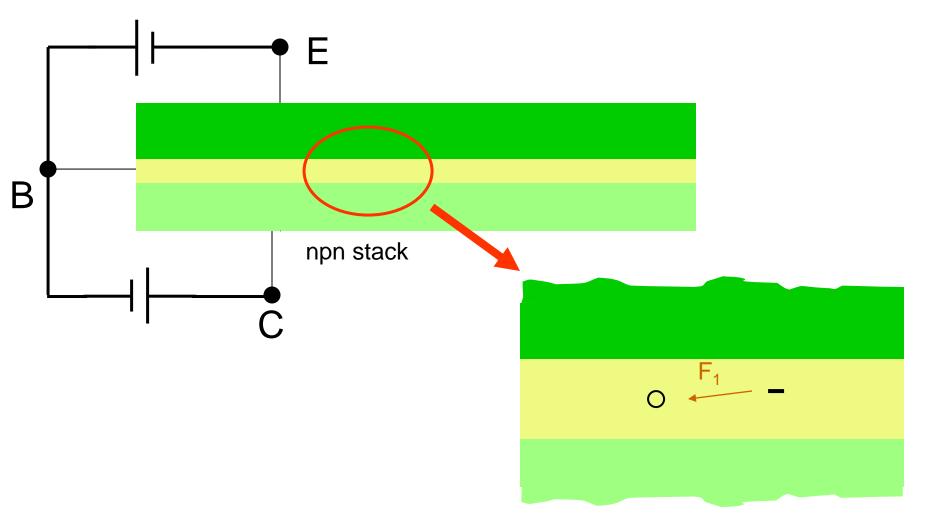
Under forward BE bias and reverse BC bias current flows into base region

Carriers in emitter are electrons (majority carriers)

When electrons pass into the base they become minority carriers

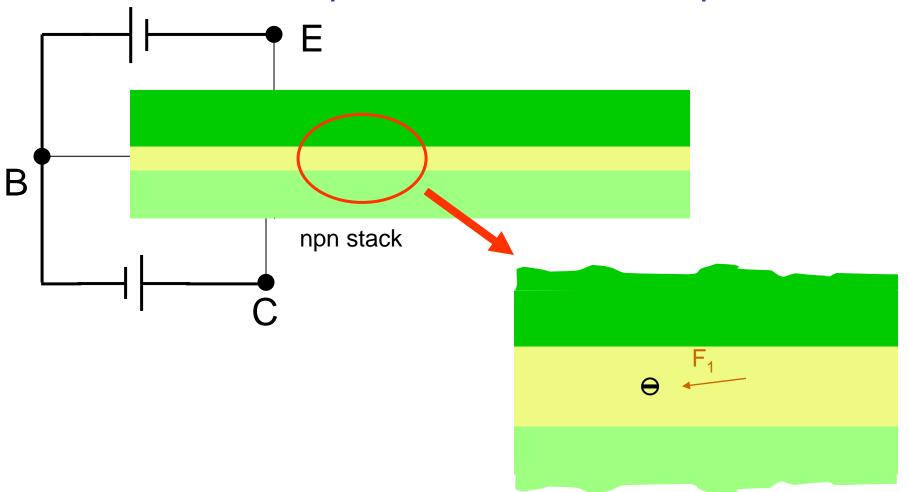
When minority carriers are present in the base they can be attracted to collector

Bipolar Operation Consider npn transistor – Forward Active Operation



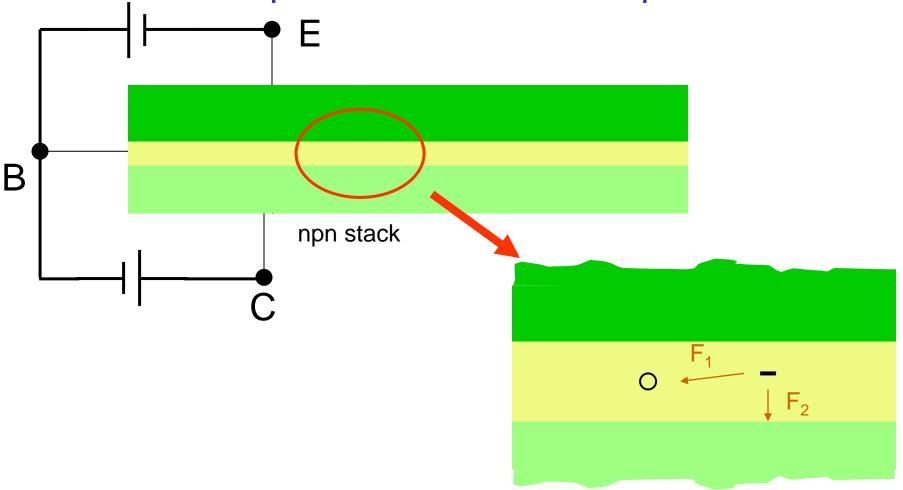
If no force on electron is applied by collector, electron will contribute to base current

Consider npn transistor – Forward Active Operation



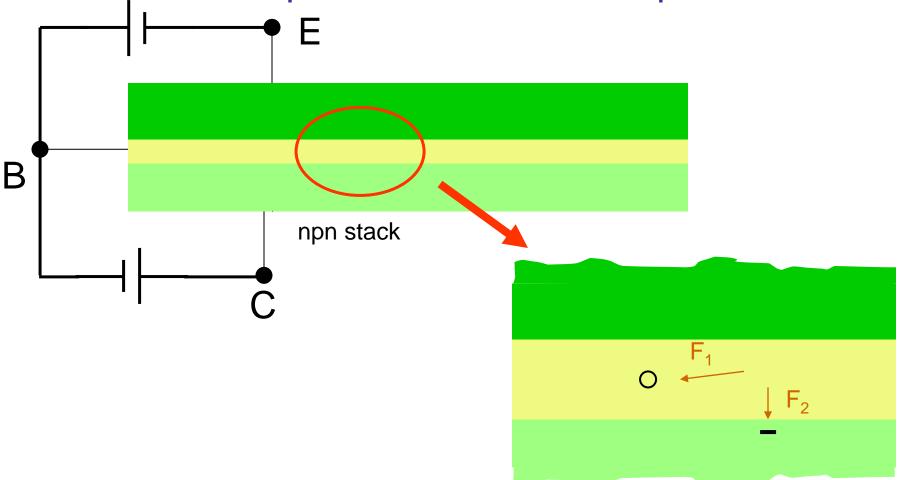
If no force on electron is applied by collector, electron will contribute to base current Electron will recombine with a hole so dominant current flow in base will be by majority carriers

Consider npn transistor – Forward Active Operation



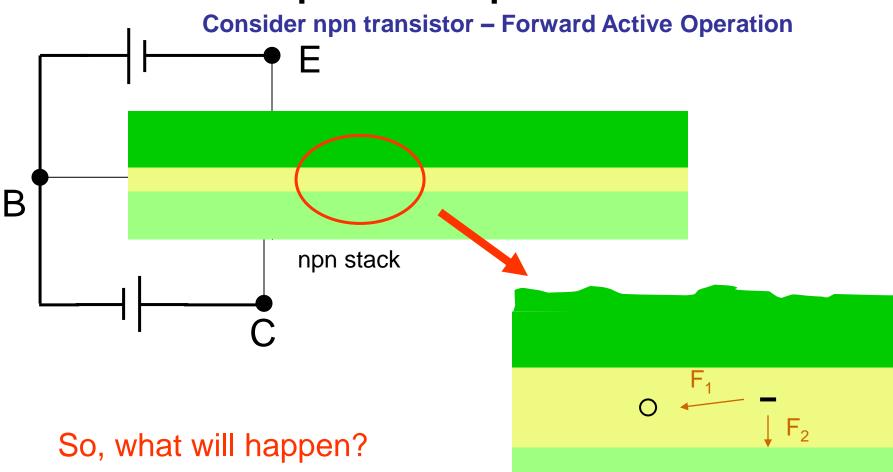
When minority carriers are present in the base they can be attracted to collector with reverse-bias of BC junction and can move across BC junction

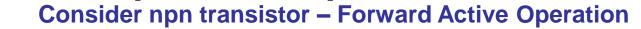


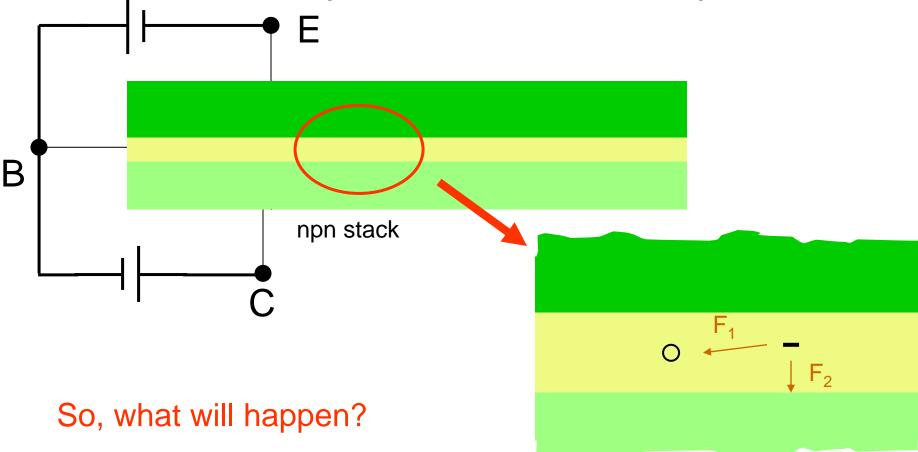


When minority carriers are present in the base they can be attracted to collector with reverse-bias of BC junction and can move across BC junction

Will contribute to collector current flow as majority carriers

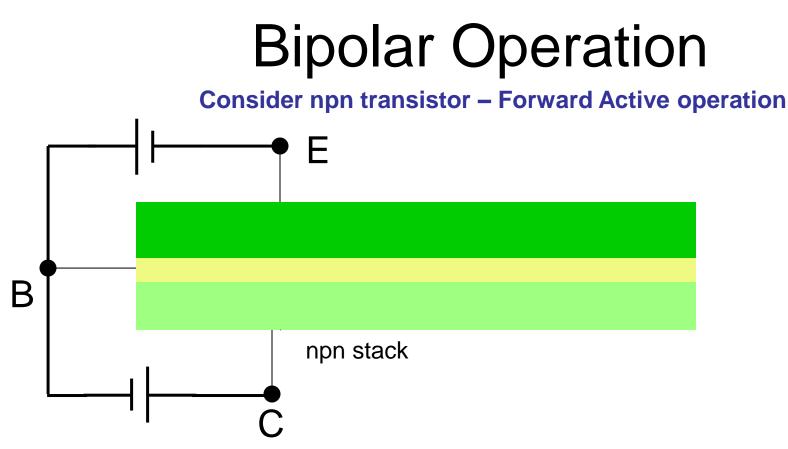






Some will recombine with holes and contribute to base current and some will be attracted across BC junction and contribute to collector

Size and thickness of base region and relative doping levels will play key role in percent of minority carriers injected into base contributing to collector current



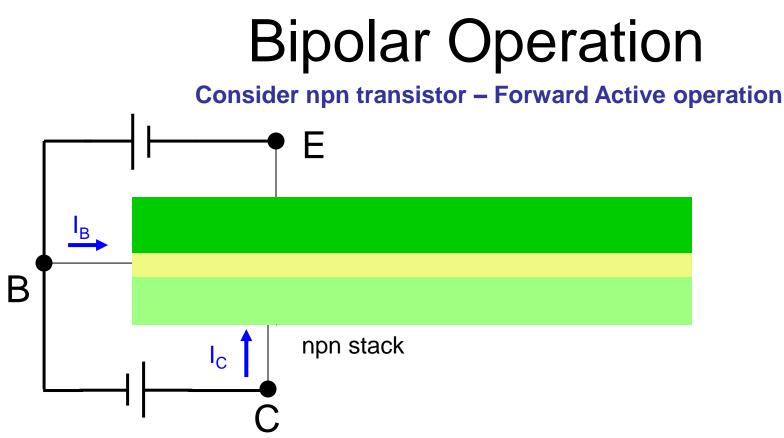
Under forward BE bias and reverse BC bias current flows into base region

Carriers in emitter are electrons (majority carriers)

When electrons pass into the base they become minority carriers

When minority carriers are present in the base they can be attracted to collector

Minority carriers either recombine with holes and contribute to base current or are attracted into collector region and contribute to collector current

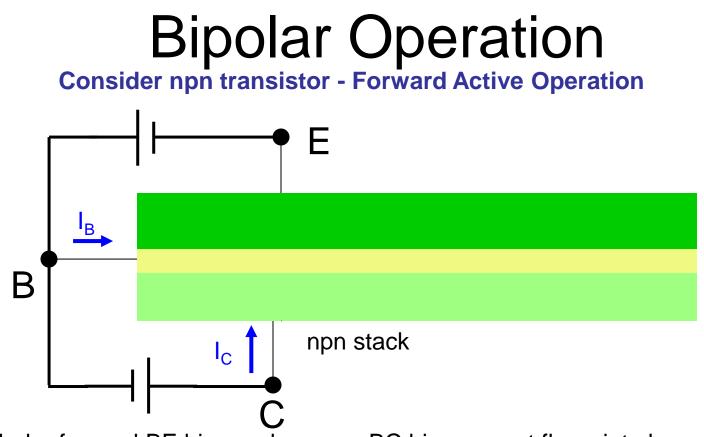


Minority carriers either recombine with holes and contribute to base current or are attracted into collector region and contribute to collector current

If most of the minority carriers are attracted to collector, $|I_c| \simeq |I_E|$ Thus $I_B << I_C$

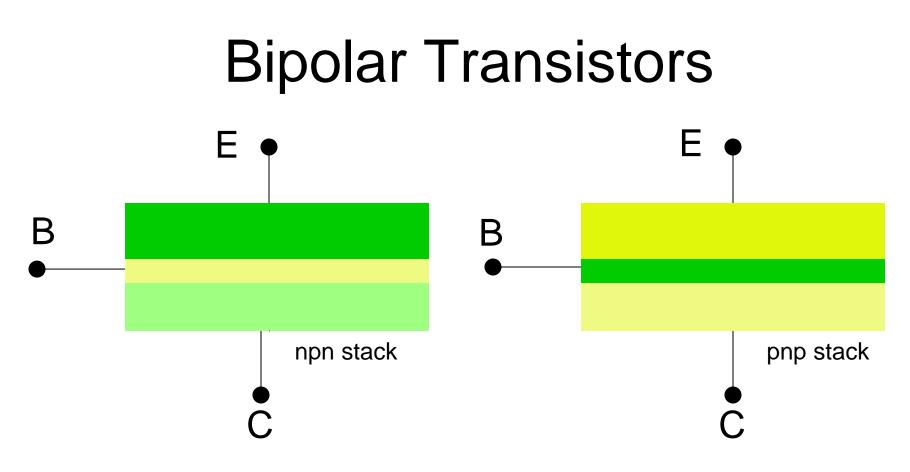
Implications of this observation?

If input to device is I_B and output is I_C , the BJT will behave as a current amplifier with large current gain !! This was the key observation by Bell Labs in 1948 !!



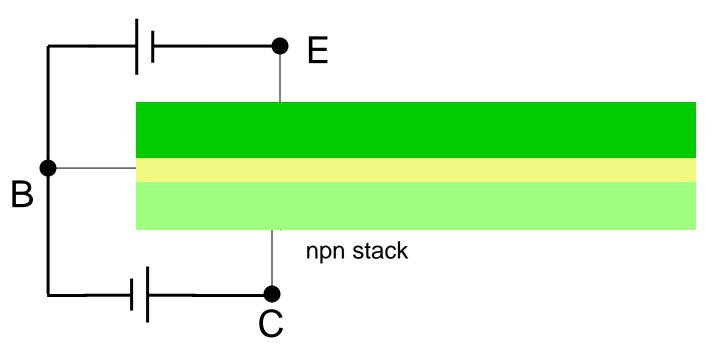
Under forward BE bias and reverse BC bias current flows into base region

- Efficiency at which minority carriers injected into base region and contribute to collector current is termed $\boldsymbol{\alpha}$
- α is always less than 1 but for a good transistor, it is very close to 1
- For good transistors $.99 < \alpha < .999$
- Making the base region very thin makes α large



- principle of operation of pnp and npn transistors are the same
- minority carriers in base of pnp are holes
- npn usually have modestly superior properties because mobility of electrons is larger than mobility of holes

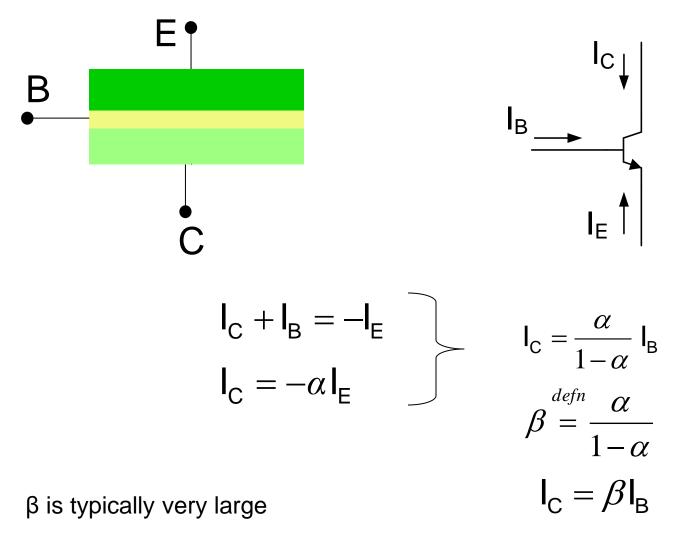
Bipolar Operation Consider npn transistor – Forward Active Operation



In contrast to MOS devices where current flow in channel is by majority carriers, current flow in the critical base region of bipolar transistors is by minority carriers

Bipolar Operation

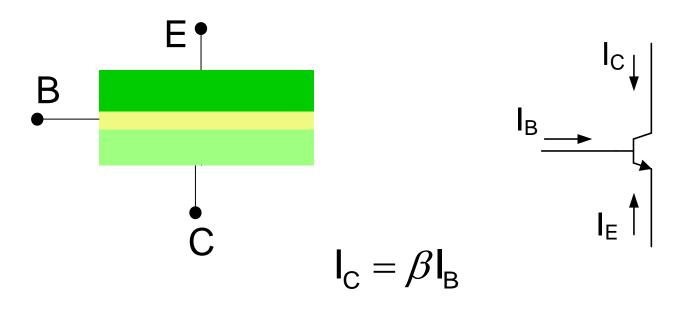
Consider npn transistor – Forward Active Operation



often 50<β<999

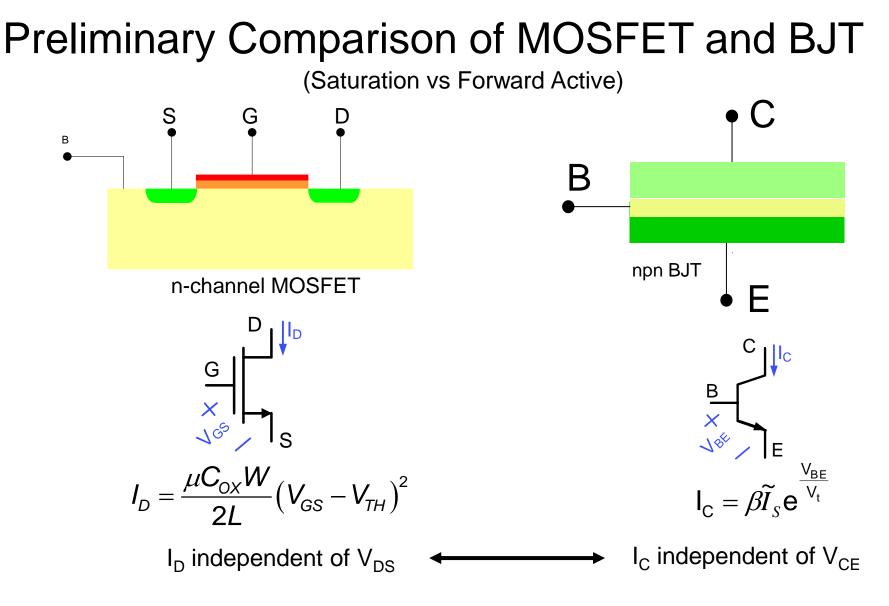
Bipolar Operation

Consider npn transistor – Forward Active Operation



 β is typically very large

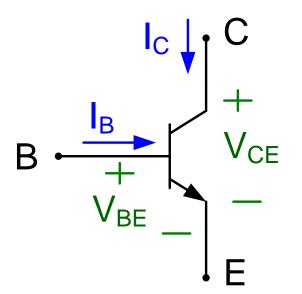
Bipolar transistor can be thought of a current amplifier with a large current gain In contrast, MOS transistor is inherently a tramsconductance amplifier Current flow in base is governed by the diode equation $I_{B} = \tilde{I}_{S} e^{\frac{V_{BE}}{V_{t}}}$ Collector current thus varies exponentially with V_{BE} $I_{C} = \beta \tilde{I}_{S} e^{\frac{V_{BE}}{V_{t}}}$



- The BJT I/O relationship is exponential in contrast to square-law for MOSFET
- Provides a very large "gain" for the BJT (assuming input is voltage and output is current)
- This property is very useful for many applications

Bipolar Models

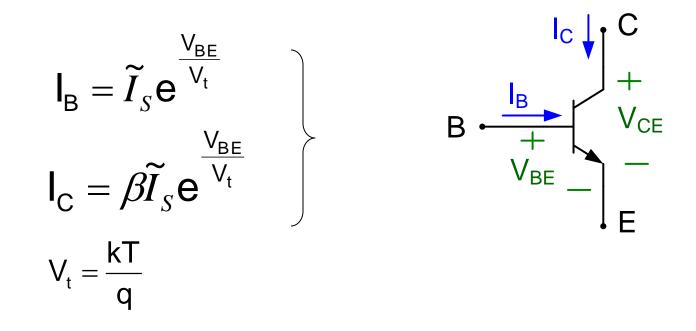
Simple dc Model



Following convention, pick I_C and I_B as dependent variables and V_{BE} and V_{CE} as independent variables

Consider npn transistor – Forward Active Operation

Summary:

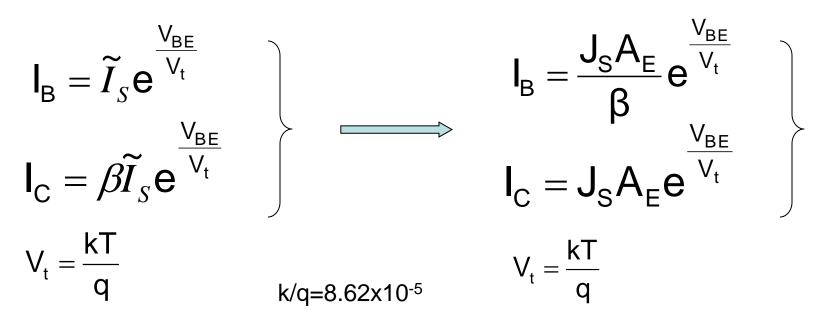


This has the properties we are looking for but the variables we used in introducing these relationships are not standard

It can be shown that \widetilde{I}_{S} is proportional to the emitter area A_E

Define J_s by $\tilde{I}_s = \beta^{-1} J_s A_E$ and substitute this into the above equations

npn transistor – Forward Active Operation



J_S is termed the saturation current density

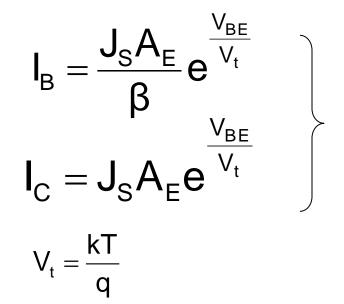
Process Parameters : J_S,β

Design Parameters: A_E

Environmental parameters and physical constants: k,T,qAt room temperature, V_t is around 26mV

J_s very small – around .25fA/u² at room temperature

npn transistor – Forward Active Operation



$$\mathbf{J}_{s} = \mathbf{J}_{sx} \left[\mathbf{T}^{m} \mathbf{e}^{\frac{-\mathbf{V}_{go}}{\mathbf{V}_{t}}} \right]$$

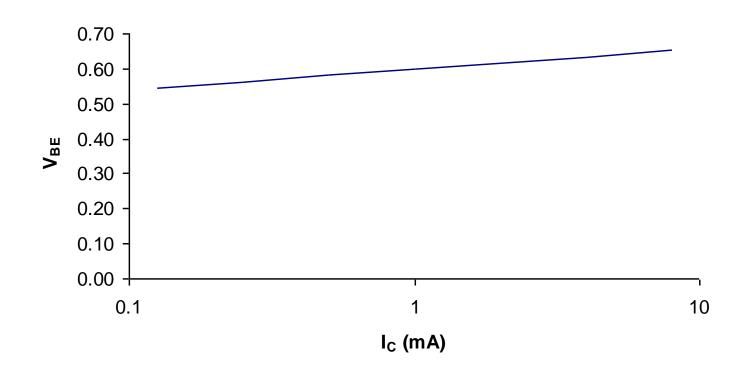
Typical values for parameters: $J_{SX}=20mA/\mu^2$, $V_{G0}=1.17V$, m=2.3

The parameter β is also somewhat temperature dependent but much weaker temperature dependence than J_{SX} .

Transfer Characteristics

npn transistor – Forward Active Operation

 J_{S} =.25fA/u² A_E=400u²

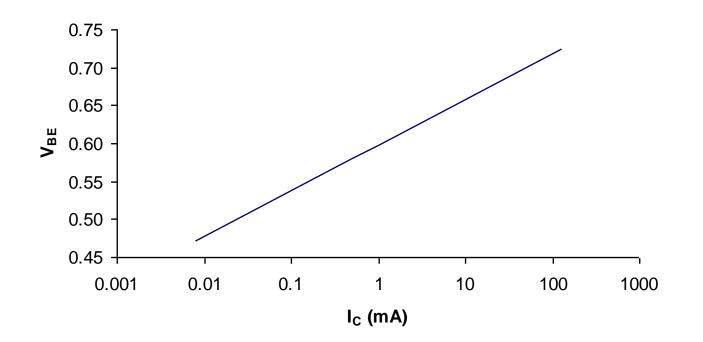


 V_{BE} close to 0.6V for a two decade change in I_{C} around 1mA

Transfer Characteristics

npn transistor – Forward Active Operation

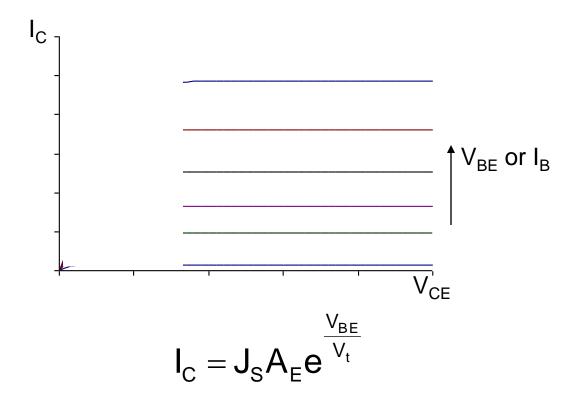
 J_{S} =.25fA/u² A_E=400u²



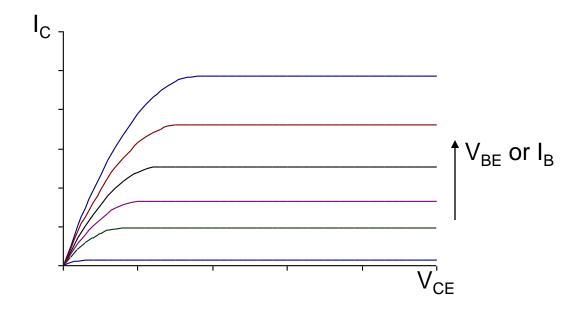
 V_{BE} close to 0.6V for a four decade change in I_{C} around 1mA

npn transistor – Forward Active Operation

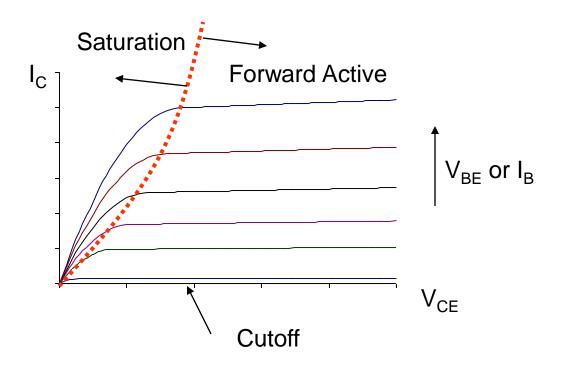
Output Characteristics



Better Model of Output Characteristics



Typical Output Characteristics



Forward Active region of BJT is analogous to Saturation region of MOSFET Saturation region of BJT is analogous to Triode region of MOSFET



Stay Safe and Stay Healthy !

End of Lecture 19